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Experimental determination of the valence band offsets of ZnGeN₂ and (ZnGe)_{0.94}Ga_{0.12}N₂ with GaN

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Abstract

A predicted type-II staggered band alignment with an approximately 1.4 eV valence band offset at the ZnGeN₂/GaN heterointerface has inspired novel band-engineered III-N/ZnGeN₂ heterostructure-based device designs for applications in high performance optoelectronics. We report on the determination of the valence band offset between metalorganic chemical vapor deposition grown (ZnGe)_{1-x}Ga_{2x}N₂, for x = 0 and 0.06, and GaN using x-ray photoemission spectroscopy. The valence band of ZnGeN₂ was found to lie 1.45–1.65 eV above that of GaN. This result agrees well with the value predicted by first-principles density functional theory calculations using the local density approximation for the potential profile and quasiparticle self-consistent GW calculations of the band edge states relative to the potential. For (ZnGe)_{0.94}Ga_{0.12}N₂ the value was determined to be 1.29 eV, ~10%–20% lower than that of ZnGeN₂. The experimental determination of the large band offset between ZnGeN₂ and GaN provides promising alternative solutions to address challenges faced with pure III-nitride-based structures and devices.

Keywords: ZnGeN₂, ZnGeGa₂N₄, II-IV-N₂, band offset, MOCVD

(Some figures may appear in color only in the online journal)

1. Introduction

 $ZnGeN_2$ is the II-IV-N₂ analogue of wurtzite GaN in which half of the cation sites are occupied by Zn and the other half by Ge. Thermodynamically, the most stable phase of ZnGeN₂ has a wurtzite-derived orthorhombic Pna2₁ (also called Pbn2₁) space group. The band gap of this phase has been predicted to be within about 0.1 eV of that of GaN [1, 2]. Measurements of the band gap of ZnGeN₂ by photoluminescence and absorption spectroscopy are consistent with this prediction [3–5]. In addition, ZnGeN₂ is almost lattice matched to GaN [1, 2, 5–7]. The large band offset between these two materials predicted using density

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functional theory (DFT) calculations has been the enabling factor for the calculated remarkable efficiency improvement in recently proposed III-N/ZnGeN₂ heterostructure-based light-emitting diodes (LEDs) [8], quantum cascade lasers [9] and UV LEDs [10].

To date only calculations of the valence band offset (VBO) between the $Pna2_1$ phase of pure $ZnGeN_2$ and GaN have been reported. Punya et al [11, 12] used DFT employing the local density approximation (LDA) for the electrostatic potential profile, and quasiparticle self-consistent GW calculations (where G is the one-electron Green's function and W the screened Coulomb interaction) for the band edge positions relative to the average electrostatic potential in each material. They included the strain effects in ZnGeN₂ to match the in-plane lattice constant to the unstrained GaN substrate. They found that the valence band maximum (VBM) of ZnGeN2 lies well above that of GaN [11, 12]: the predicted VBO at the ZnGeN₂/GaN heterointerface with the normals along the $Pbn2_1$ [100], [010] and [001] directions were reported to be 1.44 eV, 1.36 eV, and 1.38 eV, respectively [12]. On the other hand, the 'natural' VBO was determined from the calculated electron affinity values to be 0.49 eV for the (100) orientation of $Pbn2_1$ ZnGeN₂ [13]. The effect of the Zn 3d bands on the VBM can explain the positive VBO, with the valence band of ZnGeN₂ above that of GaN [11, 14]. The Zn 3d bands have stronger hybridization than the Ga 3d bands since they lie significantly closer to the VBM as compared to the Ga 3d bands. This situation will cause the VBM in ZnGeN₂ to move to a higher energy as compared to that in GaN [11, 14].

Recently, a DFT-based calculation using a hybrid functional [15] for surfaces combined with the electron-affinity rule found the natural VBM of $ZnGeN_2$ to be 0.28 eV below that of GaN, a result that is strikingly different from the results of [11] and [12]. The origin of this discrepancy is presently not clear.

Compared to GaN, the development of ZnGeN₂ is still at a very early stage. There have been only a handful of reports on the growth of ZnGeN2 thin films. These include halide vapor phase epitaxy growth on sapphire [6], metalorganic chemical vapor deposition (MOCVD) growth on sapphire with (0001) c- [7, 16], (11-20) r- [5, 7, 16], and (10-12) a- [16] out-of-plane orientations as well as on GaN/c-sapphire templates [17], and molecular beam epitaxy growth on GaN/c-sapphire templates [18]. MOCVD growth of $(ZnGe)_{1-x}Ga_{2x}N_2$ thin films on *c*- and *r*-plane sapphire as well as GaN/c-sapphire was also reported [19]. Experimental investigations of ZnGeN2 have mainly focused on the morphological [5, 16–19], optical [3, 5, 16, 17, 20], crystal structural [5, 7, 16–21], and lattice vibrational properties [21–23]. Deeplevel defects in MOCVD-grown ZnGeN2 films on sapphire substrates have also been investigated [24]. Here we report on measurements of the VBOs of $(ZnGe)_{1-x}Ga_{2x}N_2$ with GaN for x = 0 (ZnGeN₂) and x = 0.06 ((ZnGe)_{0.94}Ga_{0.12}N₂) at the respective heterointerfaces using x-ray photoemission spectroscopy (XPS).

2. Experimental details

2.1. MOCVD growth

For this study, two ZnGeN₂ and two $(ZnGe)_{1-r}Ga_{2r}N_2$ samples were grown on commercially purchased GaN/c-sapphire templates in a custom-designed dual chamber vertical-flow, rotating-disc MOCVD system having a showerhead gas injection configuration. Diethylzinc (DEZn), germane (GeH₄) and ammonia (NH₃) were used as the precursors for Zn, Ge, and N, respectively. Nitrogen (N2) was used as the carrier gas. The total reactor pressure was set at 500 Torr. The DEZn/GeH₄ molar flow rate was optimized for obtaining single crystalline thin films with stoichiometric cation composition (Zn/(Zn + Ge) = 0.5) and smooth surface morphology. The detailed growth technique was reported in [17]. Two ZnGeN₂ samples were grown on GaN templates at growth temperature $T_{\rm G} = 650$ °C, for 10 s and 80 s, using the same growth conditions for both. Two $(ZnGe)_{1-x}Ga_{2x}N_2$ samples were grown at $T_{\rm G} = 735$ °C for 23 s and 165 s on GaN templates. An in-situ reflectometer was used to estimate the thicknesses of the films. Growth rates were also confirmed from cross-sectional scanning electron microscopy (SEM) images of thicker films. The thicknesses of the ZnGeN₂ samples were ~ 2 nm and ~ 16 nm for the growth durations of 10 s and 80 s, respectively whereas the thicknesses of the $(ZnGe)_{1-x}Ga_{2x}N_2$ samples were ~ 3 nm and ~ 20 nm for the growth durations of 23 s and 165 s, respectively. It is shown later that, for XPS measurements, the 16 nm thick ZnGeN₂ and the 20 nm thick $(ZnGe)_{1-x}Ga_{2x}N_2$ films work as bulk ZnGeN₂ and bulk $(ZnGe)_{1-x}Ga_{2x}N_2$, respectively, whereas the 2 nm thick $ZnGeN_2$ and the 3 nm thick $(ZnGe)_{1-x}Ga_{2x}N_2$ films work as ZnGeN₂/GaN and (ZnGe)_{1-x}Ga_{2x}N₂/GaN heterostructures, respectively.

2.2. Materials characterization

The quality of the heterointerfaces was investigated using high magnification scanning transmission electron microscopy (STEM) images captured by a Thermofisher probecorrected Titan STEM operated at 300 kV. SEM imaging were carried out by a Helios Nanolab 600 and an FEI Apreo LoVac analytical SEM. Surface roughness of the films were determined from atomic force microscopy (AFM) images using a Bruker Icon 3 AFM. X-ray diffraction (XRD) measurements were carried out using a Bruker D8 Discover XRD with the Cu K α source. The XPS measurements on the ZnGeN₂ samples were carried out using a PHI 5000 VersaProbeTM system equipped with a scanning XPS microprobe x-ray source with hv (Al K α) = 1486.6 eV, full width at half maxima (FWHM) ≤ 0.5 eV. The XPS measurements on the $(ZnGe)_{1-x}Ga_{2x}N_2$ samples were performed using a Kratos Axis Ultra x-ray photoelectron spectrometer using a monochromatic Al K α x-ray source, $E_{\text{photon}} = 1486.6$ eV. The measurements were performed on as-grown samples without performing additional surface cleaning before or after loading into the XPS chambers to prevent potential surface

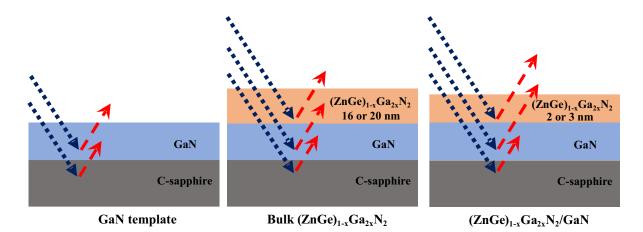


Figure 1. Schematics of the bulk GaN, bulk $(ZnGe)_{1-x}Ga_{2x}N_2$ and $(ZnGe)_{1-x}Ga_{2x}N_2/GaN$ heterostructure samples used to determine the valence band offset of $ZnGeN_2/GaN$ and $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ using XPS. The thicknesses of the bulk $ZnGeN_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ samples are 16 nm and 20 nm, respectively. The thicknesses of the $ZnGeN_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ heterostructure samples are 2 nm and 3 nm, respectively. The blue dotted lines indicate the incident x-ray beam and red dashed lines indicate the emitted photoelectrons. The arrows indicate the directions of propagation. Short red arrows indicate that the photoelectrons are absorbed before escaping from the sample.

contamination or structural damage [25]. The samples were stored in the chamber for 18 h under high vacuum prior to the XPS measurements.

3. Results and discussions

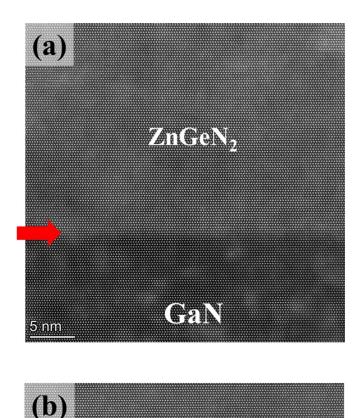
Figure 1 shows schematic diagrams of the samples. Figures 2(a) and (b) present the high magnification STEM images of a ZnGeN2 and a (ZnGe)0.94Ga0.12N2 film grown on GaN grown under identical conditions to the corresponding samples used to measure the band offsets in this work. The red arrows mark the interfaces which show clear contrasts between the substrate and the films. The STEM images demonstrate the high-quality interfaces between the binary GaN and ternary ZnGeN₂ or quaternary $(ZnGe)_{1-x}Ga_{2x}N_2$ lattices. To investigate the surface morphologies, field emission scanning electron microscopy (FESEM) images and AFM images were obtained from a \sim 350 nm thick ZnGeN₂ film and a $\sim 1 \,\mu m$ thick (ZnGe)_{1-x}Ga_{2x}N₂ film, which were grown using the identical growth conditions as those described above. Plan-view SEM images in figures 3(a) and (b) show planar surfaces for both films. The root mean square roughness values obtained from 5 μ m × 5 μ m AFM images (figures 3(c) and (d)) were 3.0 nm and 1.9 nm, respectively. Figure 3(e) shows the XRD 2θ - ω scan profile obtained from a stoichiometric ZnGeN₂ film grown on GaN/c-sapphire template. Within the scanned range ($2\theta = 30^{\circ}-90^{\circ}$), five peaks associated with GaN (002), ZnGeN₂ (002), α-Al₂O₃ (006), GaN (004), and ZnGeN₂ (004) planes were observed. The inset shows zoomed in view near the (002) and (004) peaks of GaN and $ZnGeN_2$. No peaks corresponding to secondary phases of ZnGeN₂, for example, Zn₃N₂ or Ge₃N₄ were observed. Based on the XRD 2θ - ω scan profiles, ZnGeN₂ and (ZnGe)_{1-x}Ga_{2x}N₂ thin films grown under various similar conditions to those used in this work were single crystalline and phase pure [17, 19]. The absence of secondary phases has also been confirmed by atom probe tomography measurements which has already been reported in [17]. For ZnGeN₂ films grown on GaN, very close XRD 2 θ positions of the film and the substrate (e.g. for ((002) peaks $\Delta 2\theta \sim 0.15^{\circ}$) [17]) makes it challenging to separate the signals between the two from XRD ω -rocking curves. For ZnGeN₂ films grown on *c*-sapphire substrates, an FWHM of the ω -rocking curve around the (002) peak as low as 0.28° was obtained (figure 3(f)). Crystalline quality of the ZnGeN₂ films grown on GaN (lattice mismatch < 1%) is significantly improved as compared to the ZnGeN₂ films grown on *c*-sapphire (~16% lattice mismatch). A detailed investigation of crystal structural and surface morphological properties of ZnGeN₂ films was reported in [17].

The atomic compositions of Zn, Ge, and Ga in the samples were determined using the respective 2p XPS peaks. In the ZnGeN₂ as well as the $(ZnGe)_{1-x}Ga_{2x}N_2$ samples, the Zn/(Zn + Ge) compositions were close to the stoichiometric value (0.50 ± 0.07). The Ga/(Zn + Ge + Ga) compositions in the 20 nm thick $(ZnGe)_{1-x}Ga_{2x}N_2$ sample was 0.12 ± 0.02, which corresponds to x = 0.06 in $(ZnGe)_{1-x}Ga_{2x}N_2$. Hereafter, the $(ZnGe)_{1-x}Ga_{2x}N_2$ samples will be referred to as $(ZnGe)_{0.94}Ga_{0.12}N_2$. The out-of-plane orientation of $(ZnGe)_{1-x}Ga_{2x}N_2$ (x = 0, 0.06) films grown on GaN/*c*-sapphire is (001). Therefore, the measured VBO values correspond to a (001) $(ZnGe)_{1-x}Ga_{2x}N_2/(001)$ GaN heterointerface.

The VBO, ΔE_V , between two materials A and B can be determined by using Kraut's method [26] according to which

$$\Delta E_{\rm v} = \left(E_{\rm CL,b}^{\rm B} - E_{\rm v}^{\rm B}\right) - \left(E_{\rm CL,b}^{\rm A} - E_{\rm v}^{\rm A}\right) - \left(E_{\rm CL,i}^{\rm B} - E_{\rm CL,i}^{\rm A}\right) \quad (1)$$

where, $E_{CL,b}^{A/B}$ is the binding energy of the core level in the bulk material A/B, $E_{CL,i}^{A/B}$ is the binding energy of the core level of the material A/B determined from the heterostructure between A and B and $E_V^{A/B}$ is the position of the VBM in the bulk material A/B. The positions of the core levels are determined with respect to the Fermi level. A positive value of ΔE_v would indicate the VBM of B to be above that of A.



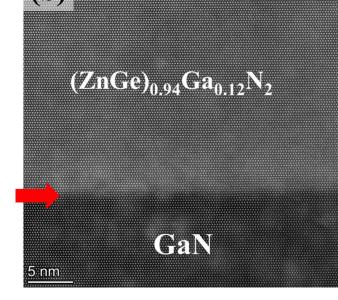


Figure 2. High magnification STEM images showing the interfaces of (a) a ZnGeN₂ film and (b) a $(ZnGe)_{1-x}Ga_{2x}N_2$ film on GaN. The interface is marked by the red arrows.

XPS is a commonly used technique to determine the parameters in equation (1) [27–29]. The parameters in the first two terms in equation (1) are determined using XPS measurements of the bulk samples of materials A and B. The parameters in the third term are determined using XPS measurement of a heterostructure formed between the two materials. In order to be able to measure the core level of the bottom layer of the two-layer heterostructure using XPS, the photoelectrons from this layer need to be detected. A thick top layer can absorb all of the photoelectrons emitted from the bottom layer due to the finite escape depth of the photoelectrons [25, 27, 30], as illustrated in figure 1. Therefore, the top layer needs to be sufficiently thin so that a reasonable number of photoelectrons from the bottom layer can escape and be detected.

With a view to determining the band offset between ZnGeN₂ and GaN at a ZnGeN₂/GaN heterointerface, XPS measurements were performed on the GaN template, the 16 nm thick ZnGeN₂ layer and the 2 nm thick ZnGeN₂/GaN heterostructure samples. The binding energies of the adventitious C 1s peaks in these three samples were measured to be 283.9 eV, 286.1 eV, and 284.9 eV, respectively. Figures 4(a)-(c) present the XPS spectra near the Ge 2p, Ga 2p and Zn 2p core-level positions, respectively, for all three samples. As can be seen here, the Ga 2p peak is absent in the spectra from the 16 nm thick ZnGeN₂ sample, which indicates that this sample has sufficient thickness to be characteristic of bulk ZnGeN₂. In addition, only the Ga 2p peak was observed in the XPS spectra of the GaN template. The XPS spectra of the 2 nm thick ZnGeN₂/GaN sample showed Ge 2p and Zn 2p as well as Ga 2p peaks. Therefore, this sample is characteristic of ZnGeN₂/GaN heterostructures. The XPS spectra near the Ge 3d, Ga 3d, and Zn 3d bands obtained from the GaN, 16 nm thick ZnGeN2 and 2 nm thick ZnGeN2/GaN heterostructure samples are shown in figures 4(d)-(f), respectively, by the black circles. The blue dashed lines were fitted to the peaks by assuming a Voigt line shape and Shirley background. The Shirley backgrounds are shown by the green dash-dot curves. The Zn 3d peaks overlapped with the N 2p peaks for both the 16 nm thick ZnGeN₂ and the 2 nm thick ZnGeN₂/GaN heterostructure samples, shown in figures 4(e) and (f), respectively. For the GaN sample (magenta spectra), only the Ga 3d peak, at a binding energy of 18.6 eV, was observed. On the other hand, for the $ZnGeN_2$ sample (blue spectra), only the Ge 3d and Zn 3d peaks were observed, at binding energies 33.0 eV and 11.4 eV, respectively. All three (Ge, Ga, and Zn) 3d peaks were observed in the spectra from the 2 nm ZnGeN2/GaN heterostructure sample (red spectra), at binding energies 31.9 eV, 20.25 eV and 10.5 eV, respectively. The FWHM values were 1.0 eV for Ga 3d peaks in figures 4(d) and (f), 1.7 eV for Ge 3d peaks and 1.6-1.7 eV for Zn 3d peaks. Please note that no corrections in the peak positions were done since only the differences between the spectral features from any given sample are used to calculate the VBO, namely, core level differences between GaN substrate and ZnGeN2 overlayer on the one hand and VBM vs. the same core levels from separate bulk-like samples (GaN substrate and thick ZnGeN₂ sample) on the other hand. Any offset in absolute binding energies between different samples in equation (1) will be cancelled out. This is precisely the advantage of the Kraut method. The measured binding energies for the core levels are within the range of corresponding values reported previously [28].

As noted earlier, the binding energies of the Zn and Ge core levels obtained from the ZnGeN₂ sample give $E_{CL,b}^{ZnGeN_2}$, the binding energies of the Ga core levels obtained from the GaN sample give $E_{CL,b}^{GaN}$. The corresponding values from the 2 nm thick ZnGeN₂/GaN heterostructure sample give $E_{CL,i}^{ZnGeN_2}$

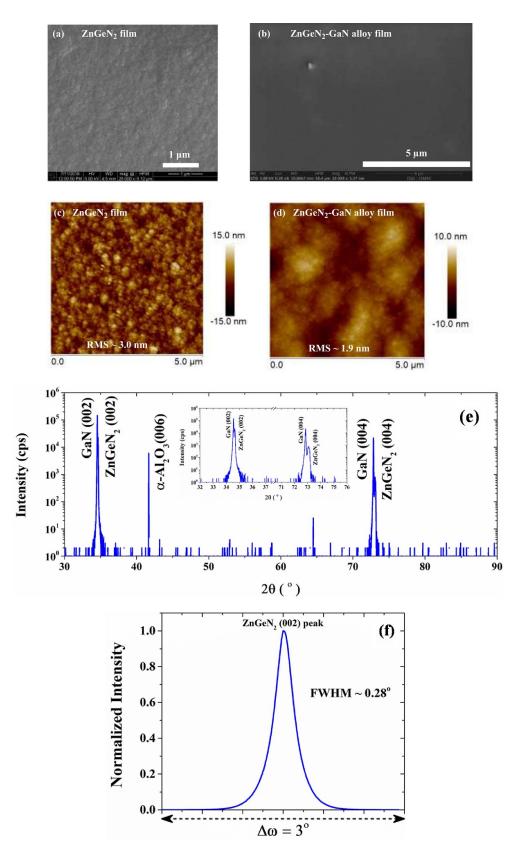


Figure 3. (a), (b) Plan-view FESEM images and (c), (d) $5 \ \mu m \times 5 \ \mu m$ AFM images of a ~350 nm thick ZnGeN₂ film (a), (c) and a ~1 μm thick (ZnGe)_{1-x}Ga_{2x}N₂ film (b), (d) grown using identical growth conditions as those used for determining the valence band offset in this work. (e) XRD 2θ - ω scan profile obtained from a ZnGeN₂ film with stoichiometric cation composition grown on GaN/*c*-sapphire template for a 2θ range from 30° to 90°. The inset shows the zoomed in view around the ZnGeN₂ (002) and (004) peaks to clearly show the separation with respective GaN peaks. (f) ω -rocking curve around the ZnGeN₂ (002) peak obtained from a single crystalline ZnGeN₂ film grown on *c*-sapphire.

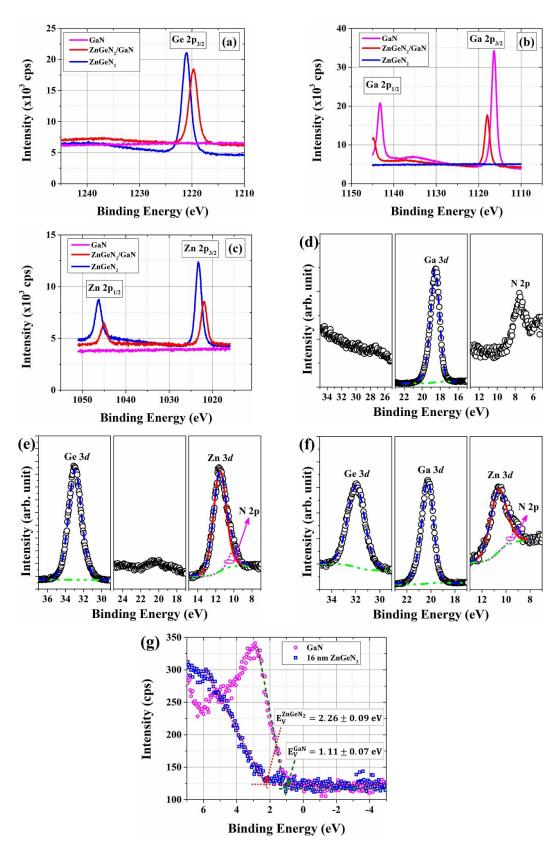


Figure 4. The XPS spectra near the (a) Ge 2p region, (b) Ga 2p region and (c) Zn 2p region obtained from the GaN, 16 nm ZnGeN₂ and the 2 nm ZnGeN₂/GaN heterostructure samples. (d)–(f) XPS spectra near the Ge 3d (left panels), Ga 3d (center panels), and Zn 3d (right panels) bands obtained from the GaN, 16 nm ZnGeN₂ and the 2 nm ZnGeN₂/GaN heterostructure samples, respectively. The original spectra are shown by the black circles. The dashed blue curves are the fitted peaks obtained assuming a Voigt shape and Shirley background. The background is shown by the green dash-dot lines. The Zn 3d peaks overlapped with the N 2p peaks which are marked in respective panels. The full width at half maxima of the fitted peaks 1.7 eV, 1.0 eV and 1.6–1.7 eV for Ge 3d, Ga 3d and Zn 3d bands, respectively. (g) The XPS spectra showing the valence band edges of the GaN (magenta circles) and the 16 nm ZnGeN₂ (blue squares) samples.

Table 1. Positions of the bulk valence band maxima and the core Ga, Zn and Ge levels extracted from the XPS spectra, from the GaN template, the 16 nm $ZnGeN_2$ (bulk) and the 2 nm $ZnGeN_2/GaN$ (heterostructure) samples. The binding energies of the core levels were determined by peak fitting assuming a Voigt shape and Shirley background. No correction in the peak positions was done. The binding energies of adventitious C 1s peaks are listed for reference.

	С	Ga		Zn		Ge		
Sample	E_{1s} (eV)	$E_{\text{Ga}-2p3/2}$ (eV)	$E_{\mathrm{Ga-3d}} (\mathrm{eV})$	$\overline{E_{Zn-2p3/2} (eV)}$	E_{Zn-3d} (eV)	$E_{\text{Ge}-2p3/2}$ (eV)	$E_{\text{Ge}-3\text{d}} (\text{eV})$	$E_{\rm V}$ VBM (eV)
GaN	283.9	1116.4	18.6	_	_	—	_	1.1 ± 0.07
ZnGeN ₂	286.1			1023.1	11.4	1221.0	33.0	2.26 ± 0.09
ZnGeN ₂ /GaN	284.9	1118.0	20.3	1022.0	10.5	1219.7	31.9	_

or $E_{CL_i}^{GaN}$. The VBM values, E_V^{GaN} and $E_V^{ZnGeN_2}$, were obtained from the GaN and 16 nm thick ZnGeN₂ samples, respectively. Figure 4(g) presents the XPS spectra near the valence band edge of the 16 nm thick ZnGeN₂ sample and the GaN template. The VBM values were calculated from the intersection of the straight line fitted over the leading edge of the XPS spectra with the average of the flat portion of the spectra for energies above the valence band maxima. Table 1 lists the values of the VBM as well as the core level binding energies. The calculated VBO between ZnGeN2 and GaN from equation (1) is 1.45 ± 0.15 eV when Zn 3d and Ga 3d corelevel energies are used and 1.65 ± 0.15 eV when Ge 3d and Ga 3d core-level energies are used with the average being 1.55 ± 0.15 eV. The calculated VBO value using Zn $2p_{3/2}$ and Ga $2p_{3/2}$, and Ge $2p_{3/2}$ and Ga $2p_{3/2}$ core level energies is 1.54 ± 0.15 eV, and 1.74 ± 0.15 eV, respectively, which are consistent with the values calculated using corresponding 3d core-level energies. These VBO values are in reasonable agreement with those obtained from explicit interface calculations (1.4 eV) [11, 12] rather than the electron-affinity based values [13, 15].

The same approach was used to determine the VBO of (ZnGe)_{0.94}Ga_{0.12}N₂ with GaN. The XPS spectra collected from (ZnGe)_{0.94}Ga_{0.12}N₂ samples are shown in figure 5. The spectra measured from a bare piece of GaN template on which the $(ZnGe)_{0.94}Ga_{0.12}N_2$ samples were grown are also shown. The binding energies of the adventitious C 1s peaks in these three samples were measured to be 286.1 eV, 285.8 eV, and 285.6 eV, respectively. The Ge 2p and Zn 2p peaks were observed in figures 5(a) and (c), respectively, from both the 3 nm and 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ samples, but not from the GaN template. The Ga 2p peak was observed in all three samples. The 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ is sufficiently thick to absorb all of the XPS signals originating in the underlying GaN substrate. Therefore, the Ga 2p peaks in the spectra from the 20 nm thick $(ZnGe)_{0.94}Ga_{0.12}N_2$ sample, shown in blue, can be assigned to the Ga atoms in the top film. Figures 5(d)–(f) show the XPS spectra near the Ge 3d, Ga 3d, and Zn 3d bands obtained from the GaN, 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ and 3 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂/GaN heterostructure samples, respectively, in black circles. The dashed blue curves in figures 5(d)-(f) are the fitted peaks assuming Voigt peak shapes and Shirley background. The overlapped Zn 3d and N 2p peaks are marked in figures 5(e) and (f). In the case of the 20 nm thick $(ZnGe)_{0.94}Ga_{0.12}N_2$ sample in figure 5(e) two components were necessary to fit the Ge 3d peak-the peak at the lower binding energy probably corresponds to a lower charge state of Ge present in the sample [29]. The binding energies of the Ge 3d and Zn 3d peaks were determined to be 32.7 and 11.3 eV, respectively, for the 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ sample, and 32.6 eV and 11.2 eV, respectively, for the 3 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂/GaN heterostructure sample. The FWHM values were 1.4 eV for Ge 3d peaks and 1.4-1.6 eV for Zn 3d peaks. The binding energy of the Ga 3d peak was 20.9 eV in both the bulk GaN and the 3 nm thick $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ heterostructure sample. The FWHM of these Ga 3d peaks are 1.0 eV. The positions of the valence band maxima in the 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ (bulk) sample and the GaN template are marked in figure 5(g). These are at 2.49 \pm 0.02 eV and 3.68 \pm 0.05 eV, respectively. The difference (2.58 eV) between the positions of the VBM of GaN templates in figures 4(g) and 5(g) is comparable to the difference (2.2 eV) between the binding energies of the adventitious C 1s levels of the two samples, which is probably caused by the difference in electrical conductivity of the two templates. The difference in electrical conductivity can result from different concentrations of unintentional impurities in the film, for example, C, which in turn can cause shifts in the core-level positions [31]. The core energy levels and the positions of the VBM determined for the (ZnGe)_{0.94}Ga_{0.12}N₂ samples are listed in table 2. The VBO between (ZnGe)_{0.94}Ga_{0.12}N₂ and GaN calculated using either Zn or Ge 3d core levels is 1.29 ± 0.2 eV, which is 0.26 eV lower than the average VBO determined for ZnGeN₂ using the 3d core-level energies. This lowering of the VBO is attributed to the reduced effect of the Zn 3d bands in the (ZnGe)_{0.94}Ga_{0.12}N₂ compared to in ZnGeN₂. Assuming a linear dependence of the VBO with composition x of $(ZnGe)_{1-x}Ga_{2x}N_2$, the predicted VBO of $(ZnGe)_{0.94}Ga_{0.12}N_2$ from theoretically calculated VBO of ZnGeN₂ [12] would be 1.32 eV, which is very close to the experimentally determined value. The error bars in the determined VBO values are mainly due to the uncertainties in the determined VBM values. The calculated total polarization difference at the ZnGeN₂/GaN heterointerface is very small [15, 32], therefore, errors in the determined VBO values due to polarization induced band bending is expected to be small. For instance, the ZnGeN₂/GaN heterostructure VBOs, predicted by Punya et al [12], along the polar and the non-polar directions differ by <0.1 eV.

The conduction band offsets were calculated using the determined VBO values and the band gap of the materials

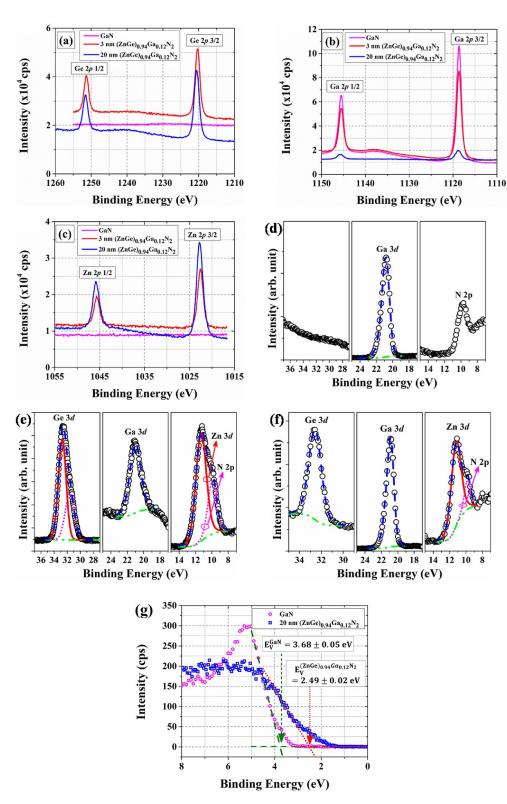


Figure 5. The XPS spectra near the (a) Ge 2p region, (b) Ga 2p region and (c) Zn 2p region obtained from the GaN, 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ and the 3 nm $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ heterostructure samples. (d–f) XPS spectra near the Ge 3d (left panels), Ga 3d (center panels), and Zn 3d (right panels) bands obtained from the GaN, 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ and the 3 nm $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ heterostructure samples. (d–f) XPS spectra near the Ge 3d (left panels), Ga 3d (center panels), and Zn 3d (right panels) bands obtained from the GaN, 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ and the 3 nm $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ heterostructure samples, respectively. The original spectra are shown by the black circles. The dashed blue curves are the fitted peaks obtained assuming a Voigt shape and Shirley background. The background is shown by the green dash-dot lines. The Zn 3d peaks overlapped with the N 2p peaks which are marked in respective panels. For the 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ sample, two components were required to fit the Ge 3d peak. The full width at half maxima of the fitted peaks 1.4 eV, 1.0 eV and 1.4–1.5 eV for Ge 3d, Ga 3d and Zn 3d bands, respectively. (g) The XPS spectra showing the valence band edges of the GaN (magenta circles) and the 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ (blue squares) sample.

Table 2. Position of the bulk valence band maxima and the core Ga, Zn and Ge levels extracted from the XPS spectra of the GaN template, the 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ (bulk) and the 3 nm $(ZnGe)_{0.94}Ga_{0.12}N_2/GaN$ (heterostructure) samples. The binding energies of the core levels were determined by peak fitting assuming a Voigt shape and Shirley background. No correction in the peak positions was done. The binding energies of adventitious C 1s peaks are listed for reference.

	С	Ga		Zn		Ge		
Sample	E_{1s} (eV)	$E_{Ga-2p3/2}$ (eV)	$E_{\mathrm{Ga-3d}} (\mathrm{eV})$	$E_{Zn-2p3/2}$ (eV)	E_{Zn-3d} (eV)	$\overline{E_{\text{Ge}-2p3/2}} \text{ (eV)}$	$E_{\text{Ge}-3\text{d}}$ (eV)	$E_{\rm V}$ VBM (eV)
GaN	286.1	1118.7	20.9	—	—	_	_	3.68 ± 0.05
(ZnGe)0.94Ga0.12N2	285.8	1118.8	21.0	1022.7	11.3	1220.5	32.7	2.49 ± 0.02
(ZnGe)0.94Ga0.12N2/GaN	285.6	1118.6	20.9	1022.6	11.2	1220.3	32.6	—

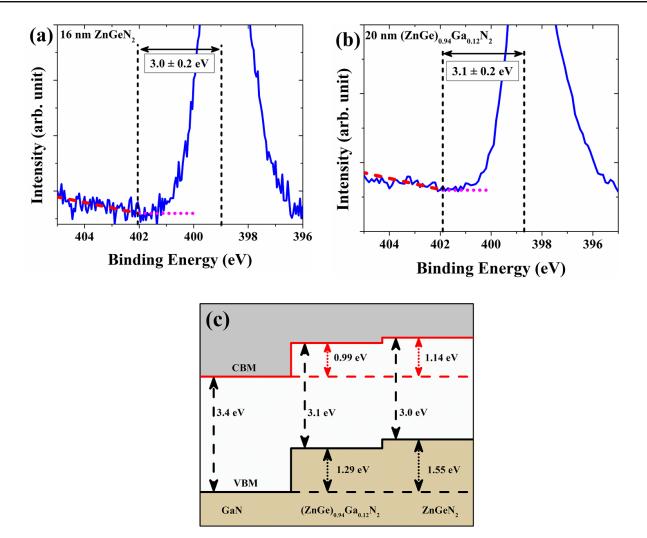


Figure 6. The XPS spectra showing the N 1s peak and onset of inelastic energy loss obtained from (a) 16 nm thick ZnGeN₂ and (b) 20 nm $(ZnGe)_{0.94}Ga_{0.12}N_2$ samples. (c) Band alignments of $(ZnGe)_{1-x}Ga_{2x}N_2$ (x = 0, and 0.06) with GaN. The average of the determined valence band offsets using the Zn 3d and Ge 3d bands were used to align the valence band maxima of $(ZnGe)_{0.94}Ga_{0.12}N_2$ and ZnGeN₂ relative to the VBM of GaN.

using the relation $\Delta E_{\rm C} = \Delta E_{\rm V} + \left(E_{\rm g}^{({\rm ZnGe})_{1-x}({\rm Ga})_{2x}{\rm N}_2} - E_{\rm g}^{{\rm GaN}}\right)$. The band gaps of ZnGeN₂ and (ZnGe)_{0.94}Ga_{0.12}N₂ were estimated by analyzing the inelastic energy loss features of N 1s peaks in the XPS spectra of 16 nm thick ZnGeN₂ and 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ samples. Before reaching the XPS detector, a photo-emitted electron can lose energy to (a) high frequency plasma oscillations in the valence band, (b) surface plasmons and (c) another electron transitioning from the valence band into the conduction band. The band-to-band

transition involves the minimum-energy process among the three, and therefore, the band gap of the material determines the lower limit of the energy loss of the photo-emitted electrons due to inelastic processes [33]. Energy loss features of the N 1s peak in XPS spectra were previously used to determine the bandgap of Si_3N_4 [34]. Figures 6(a) and (b) show the XPS spectra near the N 1s core levels obtained from the 16 nm thick ZnGeN₂ and 20 nm thick (ZnGe)_{0.94}Ga_{0.12}N₂ samples, respectively. The approximate onsets of the inelastic energy

losses were estimated by linear fitting to the energy-loss features on the higher binding energy side of the N 1s peak. The difference between the binding energies corresponding to the N 1s peak and the onset of the inelastic energy loss provides the bandgap of the epilayer. The band gaps found by this method are 3.0 \pm 0.2 eV for ZnGeN_2 and 3.1 \pm 0.2 eV for $(ZnGe)_{0.94}Ga_{0.12}N_2$. The error bars correspond to the standard deviation of the estimated onset of the inelastic energy losses. The slight increase in the band gap of the 50:50 alloy of $ZnGeN_2$ -GaN alloy ((ZnGe)_{0.5}GaN₂) as compared to those of ZnGeN2 or GaN was predicted by first-principles calculations [14]. The lower values of the band gaps as compared to the predicted values are probably due to the presence of disorder in the cation sublattice [35]. The band alignments of ZnGeN₂ and $(ZnGe)_{0.94}Ga_{0.12}N_2$ with GaN are shown in figure 6(c) using the average of the VBO values determined using the Zn 3d and Ge 3d bands.

4. Conclusions

In conclusion, the VBOs of MOCVD-grown $(ZnGe)_{1-x}Ga_{2x}N_2$ with GaN, with x = 0 and 0.06, measured using XPS, are presented for the first time to the best of our knowledge. The measured VBO for ZnGeN₂ (1.45–1.65 eV) are comparable to the predicted value from first-principles calculations using explicit interface calculations [11, 12]. For $(ZnGe)_{0.94}Ga_{0.12}N_2$, the VBO was measured to be 1.29 eV, which is very close to the predicted value from theoretically calculated VBO of ZnGeN₂ assuming a linear dependence of VBO on composition. The results from this study will expand device designs based on pure III-nitrides to III-nitrides/II-IV-N₂, which can potentially address key challenges in III-nitride based electronic and optoelectronic device technologies.

Data availability statement

The data that support the findings of this study are available from the corresponding author upon reasonable request.

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References

- Punya A, Paudel T R and Lambrecht W R L 2011 Phys. Status Solidi c 8 2492
- [2] Quayle P C, Blanton E W, Punya A, Junno G T, He K, Han L, Zhao H, Shan J, Lambrecht W R L and Kash K 2015 *Phys. Rev.* B **91** 205207
- [3] Du K, Bekele C, Hayman C C, Angus J C, Pirouz P and Kash K 2008 J. Cryst. Growth 310 1057
- [4] Suehiro T, Tansho M and Shimizu T 2017 J. Phys. Chem. C 121 27590
- [5] Misaki T, Tsuchiya T, Sakai D, Wakahara A, Okada H and Yoshida A 2002 Phys. Status Solidi c 0 188
- [6] Larson W L, Maruska H P and Stevenson D A 1974 J. Electrochem. Soc. 121 1673
- [7] Zhu L D, Maruska P H, Norris P E, Yip W and Bouthillette L O 1999 MRS Internet J. Nitride Semicond. Res. 4S1 G3.8
- [8] Han L, Kash K and Zhao H 2016 J. Appl. Phys. 120 103102
- [9] Han L, Lieberman C and Zhao H 2017 *J. Appl. Phys.* **121** 093101
- [10] Fu H, Goodrich J C, Ogidi-Ekoko O and Tansu N 2019 J. Appl. Phys. 126 133103
- [11] Punya A and Lambrecht W R L 2013 Phys. Rev. B 88 075302
- [12] Jaroenjittichai A P, Lyu S and Lambrecht W R L 2017 *Phys. Rev.* B 96 079907
- [13] Lyu S and Lambrecht W R L 2020 J. Phys. D: Appl. Phys. 53 015111
- [14] Jayatunga B H D, Lyu S, Radha S K, Kash K and Lambrecht W R L 2018 Phys. Rev. Mater. 2 114602
- [15] Adamski N L, Wickramaratne D and van de Walle C G 2020 J. Mater. Chem. C 8 7890
- [16] Karim M R, Jayatunga B H D, Feng Z, Kash K and Zhao H 2019 Cryst. Growth Des. 19 4661
- [17] Karim M R, Jayatunga B H D, Zhu M, Lalk R A, Licata O, Mazumder B, Hwang J, Kash K and Zhao H 2020 AIP Adv. 10 065302
- [18] Tellekamp M B, Melamed C L, Norman A G and Tamboli A 2020 Cryst. Growth Des. 20 1868
- [19] Jayatunga B H D, Karim M R, Lalk R A, Ohanaka O, Lambrecht W R L, Zhao H and Kash K 2020 Cryst. Growth Des. 20 189
- [20] Misaki T, Wakahara A, Okada H and Yoshida A 2004 J. Cryst. Growth 260 125
- [21] Blanton E W, He K, Shan J and Kash K 2017 J. Cryst. Growth 461 38
- [22] Blanton E W, Hagemann M, He K, Shan J, Lambrecht W R L and Kash K 2017 J. Appl. Phys. 121 055704
- [23] Peshek T, Wang S, Angus J and Kash K 2007 MRS Proc. 1040 1040
- [24] Haseman M S et al 2020 J. Appl. Phys. 127 135703
- [25] King P D C, Veal T D, Kendrick C E, Bailey L R, Durbin S M and McConville C F 2008 Phys. Rev. B 78 033308
- [26] Kraut E A, Grant R W, Waldop J R and Eowalczyk S P 1980 Phys. Rev. Lett. 44 1620
- [27] King P D C, Veal T D, Jefferson P H, McConville C F, Wang T, Parbrook P J, Lu H and Schaff W J 2007 Appl. Phys. Lett. 90 132105
- [28] Hong S-K, Hanada T, Makino H, Chen Y, Ko H-J, Yao T, Tanaka A, Sasaki H and Sato S 2001 Appl. Phys. Lett. 78 3349
- [29] Lee Y M, Jang S H, Han M and Jung M-C 2011 Appl. Phys. Lett. 99 123103

- [30] Balaz S, Zheng Z and Brillson L J 2013 J. Appl. Phys.
 114
 183701

 [31]
 Wang Z et al 2008 J. Am. Chem. Soc. 130 16366
- [32] Paudel T R and Lambrecht W R L 2009 Phys. Rev. B **79** 245205
- [33] Nichols M T, Li W, Pei D, Antonelli G A, Lin Q, Banna S, Nishi Y and Shohet J L 2014 J. Appl. Phys. 115 094105
- [34] Miyazaki S 2011 J. Vac. Sci. Technol. B 19 2212
 [35] Skachkov D, Quayle P C, Kash K and Lambrecht W R L 2016 Phys. Rev. B 94 205201